



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Michael Shu-Huan Wang, et al. Docket No: TI-34402
Serial No: 10/718,921 Conf. No: 2399
Examiner: Shantese L. McDonald Art Unit: 3723
Filed: 11/21/2003
For: CHEMICAL MECHANICAL POLISHING APPARATUS AND METHOD TO MINIMIZE
SLURRY ACCUMULATION AND SCRATCH EXCURSIONS

LETTER TO OFFICIAL DRAFTSPERSON

Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Attention: Official Draftsperson

MAILING CERTIFICATE UNDER 37 C.F.R. §1.8(a)

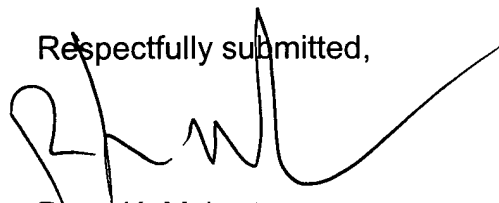
I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 4-8-05.


Ann Trent

Dear Sir:

Transmitted herewith for filing is one sheet of formal drawings for the above identified application. Charge any necessary fees to the deposit account of Texas Instruments Incorporated, Account No. 20-0668.

Respectfully submitted,



Peter K. McLarty
Attorney for Applicants
Reg. No. 44,923

Texas Instruments Incorporated
P.O. Box 655474, MS 3999
Dallas, TX 75265
(972) 917-4258



ATTORNEY: Anr Trent
DOCKET NO: TI-34402
DATE: 4-4-5
DUE DATE: 4-5-5

TEXAS INSTRUMENTS
PATENT DRAFTING

Michael Jenkins
972-917-5639
